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Substitute for Form 1449A/PTO				Application Number	Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Filing Date	Herewith
(use as many sheets as necessary)				First Named Inventor	Wan-Thai, Hsu, et al.
Sheet	1	of	2	Group Art Unit	Unknown
				Examiner Name	Unknown
				Attorney Docket Number	UOM 0210 PUSP 1

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Signature	H. Jey Tew	Date Considered	7/18/04
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

³ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. *Applicant is to place a check mark here if English language Translation is attached.

Substitute for Form 1449B/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

2

of

2

Complete If Known	
Application Number	Unknown
Filing Date	Herewith
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Group Art Unit	Unknown
Examiner Name	Unknown

Sheet	2	of	2	Attorney Docket Number	UOM 0210 PUSP 1
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OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS

Examiner Initials ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		HSU, WAN-THAI, ET AL., A Sub-Micron Capacitive Gap Process For Multiple-Metal-Electrode Lateral Micromechanical Resonators, Technical Digest, IEEE Int. Micro Electromechanical Systems Conf., Interlake, Switzerland, January 21-25, 2001, pp. 349-352.	
		HSU, WAN-THAI, ET AL., Mechanically Temperature-Compensated Flexural-Mode Micromechanical Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, Dec. 11-13, 2000, pp. 399-402.	
		CLARK, JOHN R., ET AL., High-Q VHF Micromechanical Contour-Mode Disk Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, December 11-13, 2000, pp. 493-496.	
		CLARK, JOHN R., ET AL., Measurement Techniques For Capacitively-Transduced VHF-to-UHF Micromechanical Resonators, Digest of Technical Papers, the 11 th Int. Conf. on Solid-State Sensors & Actuators, Munich, Germany, June 10-14, 2001, pp. 1118-1121.	
		C. T.-C. NGUYEN, "Micromachining technologies for miniaturized communication devices," Proceedings of SPIE: Micromachining and Microfabrication, Sept. 20-22, 1998, pgs. 24-38	
		T. HIRANO et al., "Design, Fabrication, and Operation of Submicron Gap Comb-Drive Microactuators," Journal of Microelectromechanical Systems, March 1992, No. 1, pgs. 52-59	
		J.R. TUCKER et al., "Nanoscale FETs and STM Lithography," University of Illinois, 1995, pgs. 425-434	
		C. T.-C. Nguyen, "High-Q Micromechanical Oscillators and Filters For Communications," Int'l Symposium on Circuits and Systems, June 9-12, 1997, pgs. 2825-2828	
		K. TANAKA, "Nanotechnology towards the 21 st Century," Thin Solid Films, 1999, pgs. 120-125	

Examiner Signature		Date Considered	7/8/04
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